



Electrohydrodynamic Micropump Modeling for Performance Optimization

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COMSOL
CONFERENCE
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PUMP PRINCIPLE & MECHANISM

- Electrohydrodynamic pumps

$$F = qE + P \cdot \nabla E - \frac{1}{2} E^2 \nabla \epsilon + \frac{1}{2} \nabla \left(E^2 \rho \left(\frac{\partial \epsilon}{\partial \rho} \right)_T \right)$$

- Ion-drag principle

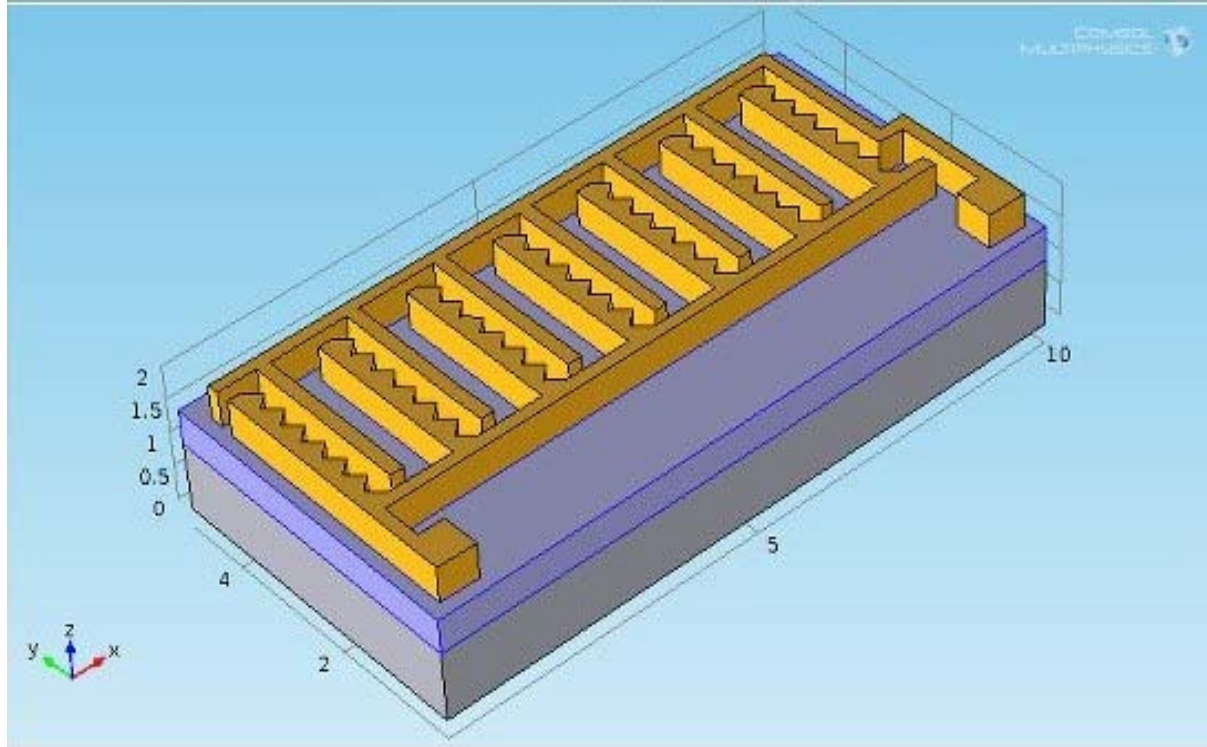
- Mechanism of the pump



BENEFITS OF EHD MICROPUMP

- Robust design
- No moving parts
- Easy to fabricate
- Miniature design
- Low power consumption

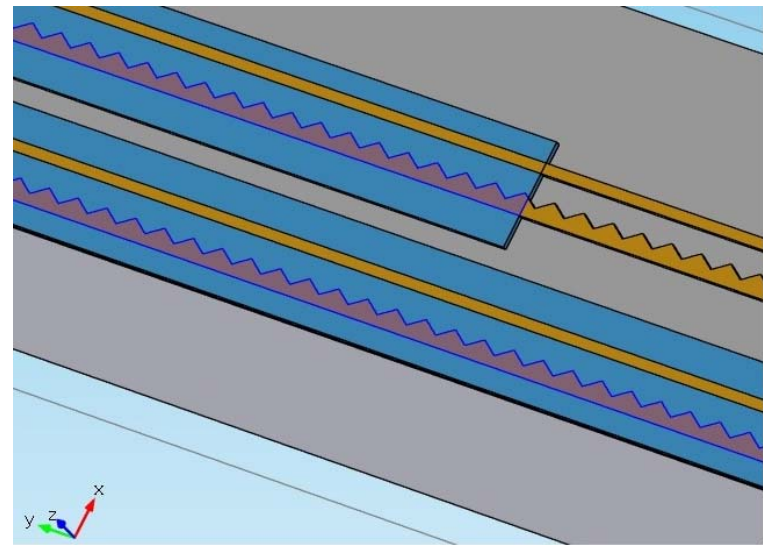
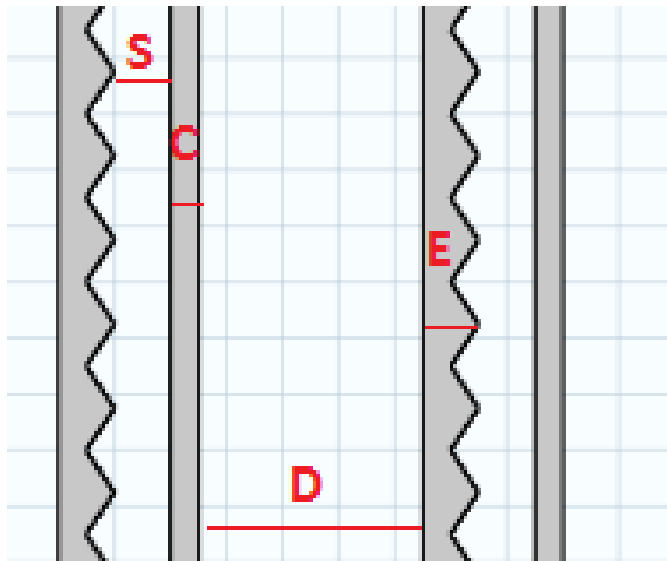
Model Prototype



Modules Used:

1. AC/DC
2. Fluid flow
3. Structural Mechanics
4. Heat Transfer

Building Geometry in COMSOL



E	C	S	D
20um	10um	20um	80um

SIMULATIONS & RESULTS

- Joule Heating results on Si-Au pair

Electrical Conductivity of water	Operating Voltage (V)	Low temperature limit (K)	High temperature limit (K)
$\sigma = 5.5e0$	5	295.41	2727.4
	10	303.08	435.19
	20	336.17	896.75
	40	436.61	2727.4
$\sigma = 5.5e-4$	20	289.03	296.31
	40	287.48	297.75
	80	291.09	326.95
$\sigma = 5.5e-6$	40	287.27	297.7
	200	291.96	465.23
$\sigma = 5.5e-8$	80	291.26	326.98
	200	291.26	326.98
$\sigma = 5.5e-16$	200	291.26	326.98

SIMULATIONS & RESULTS

- Electric Field Results

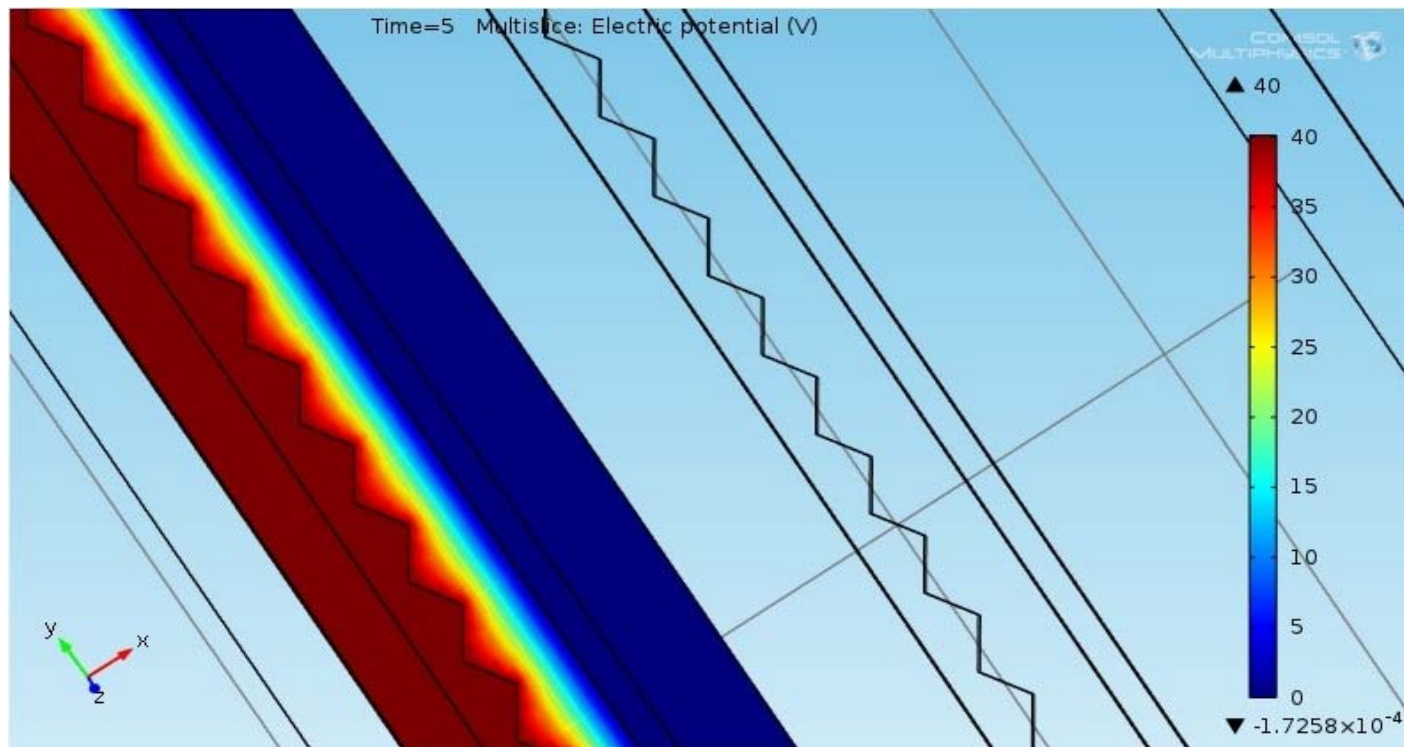


Figure showing increase in Potential gradient

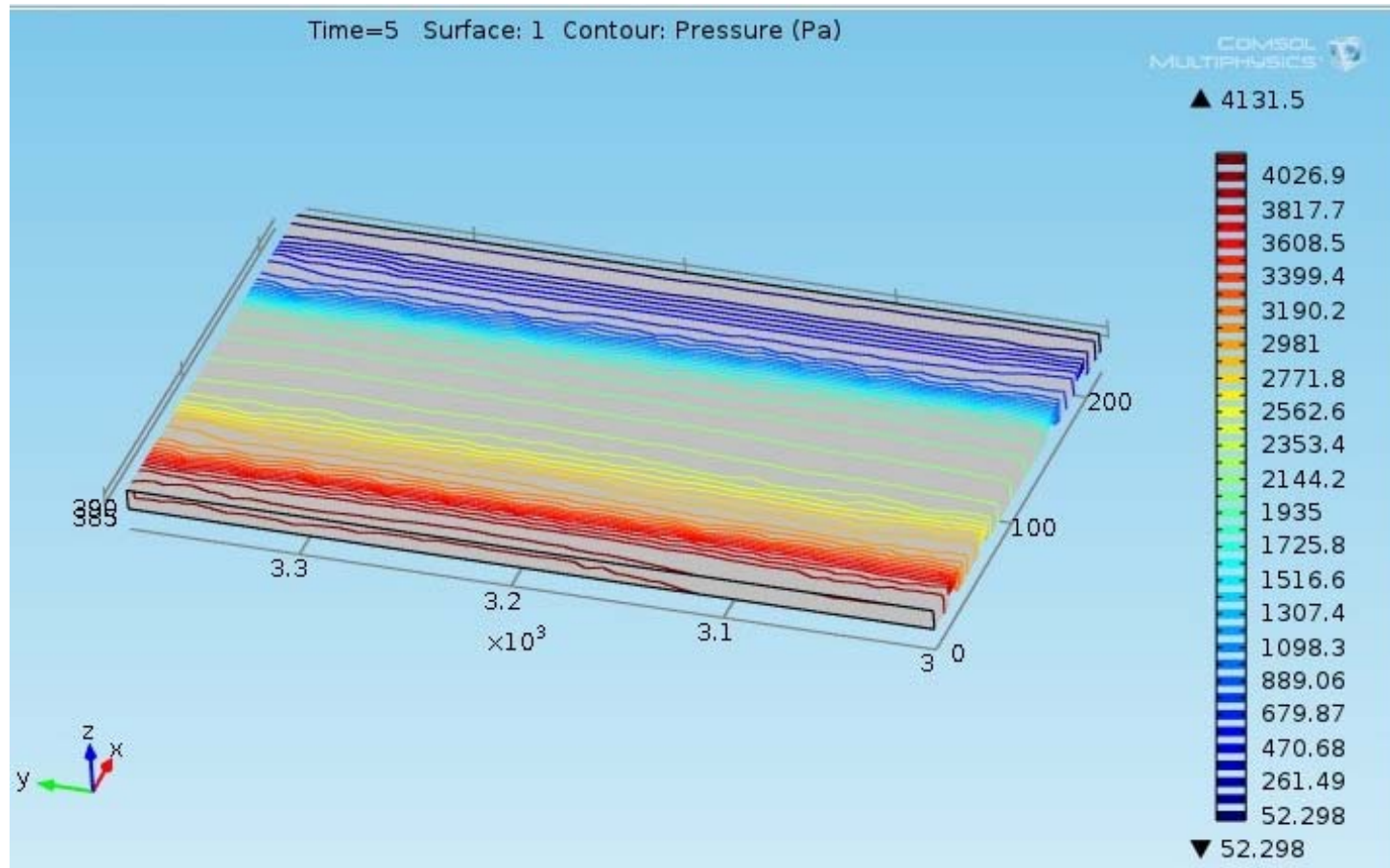
- Variation in the Electric field created



Higher Limit of Electric field : 8.43×10^{12} V/m

Lower Limit of Electric field : 8.43×10^6 V/m

- Fluid Flow & Pressure contour

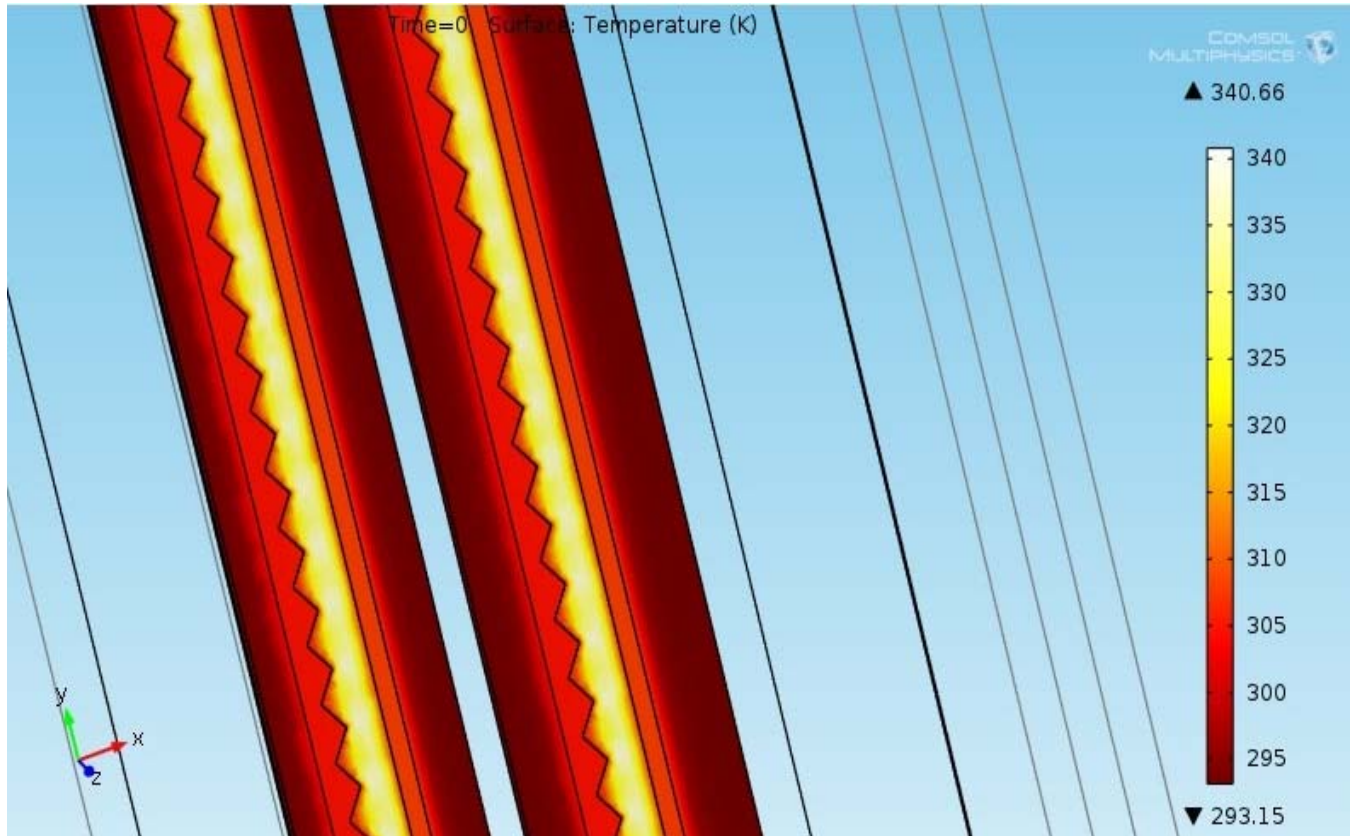


ANALYTICAL CALCULATION OF INLET VELOCITY

Maximum Velocity Obtained – 8.29m/s

Minimum Velocity Obtained – 0.0082m/s

- Varied Metal Thickness results



Au thickness – 10 μM with $V= 10\text{v}$ and $\sigma=5.5$

For Au thickness – 5 μM with $V= 10\text{v}$ and $\sigma=5.5$

$T_{\text{low}}=303.08\text{ K}$ $T_{\text{high}}=435.19\text{ K}$

OPTIMIZED DESIGN OF THE PUMP

- Minimize the joule heating
- To maximize the electric field at every point
- Thickness of the electrode
- Operating voltage range
- Fabrication of the substrate
- Current density on the electrode

APPLICATIONS

- Microfluidic systems
- Bio-MEMS and MEMS analysis systems
- Drug delivery
- On chip cooling

REFERENCES

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THANK YOU...